



Docket No.: M4065.0319/P319-A
(PATENT)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:
Ronald A. Weimer, et al.

Examiner: Thanhha S. Pham

Application No.: 09/912,558

Allowed: November 18, 2005

Filed: July 26, 2001

Art Unit: 2813

For: METHOD OF FABRICATING A
SEMICONDUCTOR DEVICE WITH A
WET OXIDATION WITH STEAM
PROCESS

COMMENTS ON EXAMINER'S STATEMENT OF REASONS FOR ALLOWANCE
UNDER 37 C.F.R. § 1.104(E)

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

Applicants have received the Examiner's Statement of Reasons for Allowance, with the November 18, 2005 Notices of Allowance and Allowability, relating to the above-identified patent application. Entry of the Examiner's Statement into the record should not be construed as any agreement with or acquiescence in the reasoning stated by the Examiner. Each of the claims stands on its own merits and is patentable because of the combination it recites and not because of the presence or absence of any one particular element.

Application No.: 09/912,558

Docket No.: M4065.0319/P319-A

The Examiner's Statement was not prepared by Applicant and only contains the Examiner's possible positions in one or more reasons for allowability. Thus, any interpretation with respect to the Examiner's Statement of Reasons for Allowance should not be imputed to the Applicants.

Dated: February 21, 2006

Respectfully submitted,

By 

Thomas J. D'Amico

Registration No.: 28,371

DICKSTEIN SHAPIRO MORIN &
OSHINSKY LLP

2101 L Street NW

Washington, DC 20037-1526